



Ocean MEMS and Related Technology

Guest Editors:

Prof. Dr. Shizhi Qian

Department of Mechanical and
Aerospace Engineering, Old
Dominion University, Norfolk, VA
23529, USA

Dr. Teng Zhou

Mechanical and Electrical
Engineering College, Hainan
University, Haikou 570228, China

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Message from the Guest Editors

Dear Colleagues,

Ocean MEMS is a fast-expanding field with many applications ranging from various MEMS sensors to energy-conversion devices. Ocean MEMS is important because of its miniaturization, low power consumption, and high integration. For example, MEMS-based instruments have been developed for measuring the conductivity, temperature, and pressure of seawater in real time. Some MEMS devices have been used to detect and separate heavy metal ions, ocean microorganisms, and other components in seawater. In addition, some systems have been developed to extract minerals such as sodium, potassium, and uranium, and to desalinate seawater. Ocean MEMS has also been used for ocean energy conversion. We invite papers related to ocean MEMS, including both fundamental studies and those on device/system development. We look forward to receiving your papers.

Prof. Dr. Shizhi Qian

Prof. Dr. Teng Zhou

Guest Editors





Editor-in-Chief

Message from the Editor-in-Chief

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Micromachines Editorial Office
MDPI, St. Alban-Anlage 66
4052 Basel, Switzerland

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